JUNE 6-9
• Basic Vacuum Technology (Four full days)

JUNE 6
• Plasma-enhanced Chemical Vapor Deposition: Fundamentals, Techniques and Application (Full day)

JUNE 6
• Fabrication of Planar Silicon CMOS Integrated Circuits (Half day: 8:30am-Noon)

JUNE 7
• Vacuum Pumps: An Introduction to their Operation and Maintenance (Full day)

JUNE 7
• Design of Experiments: Applications in Thin Film Deposition (Full day)